



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants:

MEHRDAD NIKOONAHAD ET AL.

Title: SCANNING SYSTEM FOR INSPECTION ANOMALIES ON SURFACES

Application No.: 10/666,120 Filing Date: September 19, 2003

Examiner: Unknown Group Art Unit: 2877

Docket No.: TNCR.001US4 Conf. No.: 8430

Certificate of Mailing Under 37 CFR 1.8

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Fragnito
Signature

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, Applicants call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention in this patent application.

Copies of the documents listed on the accompanying Form PTO-1449 are enclosed.

Citation of these documents shall not be construed as (1) an admission that the documents are prior art with respect to the invention or inventions claimed in this application, (2) a representation that a search has been made (other than as indicated by any cited document), or (3) an admission that the cited information is, or is considered to be, material to patentability as defined in § 1.56(b).

Attorney Docket No.: TNCR.001US4

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This information disclosure statement is submitted under 37 C.F.R. § 1.97(b) and consequently no fee should be required. The Commissioner is authorized, however, to charge any fee that may be required, or to credit any overpayment, against Deposit Account No. 502664. This form is being submitted in duplicate.

Respectfully submitted,



James S. Hsue

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3/12/04

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U.S. Department of Commerce, Patent and Trademark		Atty. Docket No.			Application No.		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		TNCR.001US4			10/666,120		
(Use several sheets if necessary)		Applicant(s)			Conf. No.		
		Nikoonahad et al.			8430		
		Filing Date			Group		
		September 19, 2003			2877		
U.S. Patent Documents							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
U.S. Published Patent Application Documents							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
Foreign Patent Documents							
						Translation	
	Document	Date	Country	Class	Subclass	Yes	No
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)							
1	Fossey, Michael E., "System Architecture and Design Next Generation Wafer Inspection System", July 25, 1994, ADE Optical Systems						
2	Fossey, Michael E.; Hunt, Jim; Clementi, Lee, "Engineering Requirements Document, Galaxy, Advanced Wafer Inspection Station", Draft Revision 0.1, June 13, 1995, ADE Optical Systems						
3	Fossey, Michael E., "Calibration, Signal & Data Processing for Galaxy AWIS Beta Units", September 26, 1996, ADE Optical Systems						
4	"AWIS, 300mm Advanced Wafer Inspection System", April 6, 1996, ADE Optical Systems						
5	"Particle Scattering Project (PSP), Work Product of SABIT Interns (3), September 27, 1995, ADE Optical Systems						
Examiner		Date Considered					
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.</p>							